

THE FAST STOCHASTIC MATCHING PURSUIT FOR NEUTRINO EXPERIMENTS

Yuyi Wang (on behalf of JNE collaboration)

Department of Engineering Physics & Center for High Energy Physics, Tsinghua University, Beijing, China wangyy21@mails.tsinghua.edu.cn



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I. Motivation

waveform $oldsymbol{w}$ event time t_0 from PMTs in analysis high resolution needed LS detector



V. Bias and resolution

The relative resolution of μ , and the resolution of t_0 are defined as

$$\eta' = \frac{\sqrt{\operatorname{Var}[\hat{\mu}]} / \operatorname{E}[\hat{\mu}]}{\sqrt{\operatorname{Var}[N_{\operatorname{PE}}]} / \operatorname{E}[N_{\operatorname{PE}}]}, \eta_t = \frac{\sqrt{\operatorname{Var}[\hat{t}_0 - t_0]}}{E[\hat{t}_0]}$$

where $N_{\rm PE}$ is number of PEs. In the **most optimistic** case, the resolution improvement of μ could be seen as the improvement of energy resolution.





The MCMC method is the upper limit of FSMP; the 1st method uses the first PE time as event time, which is biased.

III. Charge model for MCP-PMTs



There are two kinds of PE in MCP-PMTs

5000

VI. GPU acceleration

FSMP is accelerated with batched algorithm on GPU: a lot of waveforms are operated together, instead of analyzing them one by one.



Batched algorithm



Fig. 11: A sketch of the original and the batched algorithm.



Fig. 12: The batched method performs ~ 100 waveforms per second with batch size $\sim 10^3$ on NVIDIA[®]A100, and it is faster than original algorithm on CPU by more than 2 orders of magnitude.

IV. The MCMC steps in FSMP

Fast stochastic matching pursuit (FSMP, arXiv 2403.03156) [2, 3] supports any charge model constructed with multiple normal distributions, including MCP-PMTs' charge model.



VII. Summary

- Better energy resolution: up to (12.2 ± 1.4) % better ($\mu = 1$).
- Better timing resolution: unbiased, (37.5 ± 1.8) % better ($\mu = 1$).
- High performance: ~ 100 waveforms per second, ~ 1000 times faster on consumer GPUs than CPUs.

References

[1] Jun Weng et al., 2024, arXiv: 2402.13266. [2] Dacheng Xu et al. Journal of Instrumentation, 6 2022, arXiv:2112.06913. [3] Yuyi Wang et al., 2024, arXiv: 2403.03156.